

Session Title:	[MF1] Smart and Intelligent MI
Session Date:	November 14 (Mon.), 2022
Session Time:	13:00-14:35
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Tae-Hun Shim (Hanyang Univ., Korea)

[MF1-1] [Plenary] 13:00-13:45

Metrology and Inspection Challenges with EUV Patterning at Advanced Nodes
Sandip Halder (IMEC, Belgium)

[MF1-2] [Invited] 13:45-14:15

MI: The Key of Semiconductor Processes
ByoungHo Lee (Hitachi High-Tech Corp., Japan)

[MF1-3] 14:15-14:35

The Semiconductor Metrology of Mechanical, Electrical and Chemical Analysis by AFM
Sang-Joon Cho, Seongoh Kim, Ahjin Cho, and ByungWoon Ahn (Park Systems Corp., Korea)